D. Thin Film Process Technology 분과

2020년 2월 14일(금), 10:45-12:30 / Room K (다이아몬드 I, 6층)

FK2-D] Thin Film Process III

좌장: 최창환 교수 (한양대학교), 권세훈 교수 (부산대학교)

FK2-D-1 10:45-11:15	[초청] Atomic Layer Deposition Assisted Double Patterning Lithography Se-Hun Kwon School of Materials Science and Engineering, Pusan National University
FK2-D-2 11:15-11:30	Chemical and Electrical Properties of Atomic Layer Deposited HfO ₂ Using Hf(N(CH ₃) ₂) ₄ and CpHf(N(CH ₃) ₂) ₃ Precursors Sungmin Park ¹ , Bo-Eun Park ¹ , Hwi Yoon ¹ , Sanghun Lee ¹ , Taewook Nam ¹ , Taehoon Cheon ² , Soo-Hyun Kim ² , and Hyungjun Kim ¹ ¹ School of Electrical and Electronics Engineering, Yonsei University, ² School of Materials Science and Engineering, Yeungnam University
FK2-D-3 11:30-11:45	Carbon Nanotube Network Transistors Constructed from the Reuse of Semiconducting Carbon Nanotube Solution Ju Won Jeon ¹ , Yongwoo Lee ¹ , Jinsu Yoon ¹ , Hyo-Jin Kim ¹ , Geon-Hwi Park ¹ , Dong Myong Kim ¹ , Dae Hwan Kim ¹ , Min-Ho Kang ² , and Sung-Jin Choi ¹ ¹ School of Electrical Engineering, Kookmin University, ² Department of Nano-process, National Nanofab Center(NNFC)
FK2-D-4 11:45-12:00	Diffusion of Vanadium and Yttrium is Responsible for the Degradation of Vanadium Oxide Films Deposited on Y-stabilized ZrO₂ Above 500°C Songhee Choi ¹ , J. Oh ² , JH. Lee ² , J. H. Jang ² , and Shinbuhm Lee ¹ ¹ DGIST, ² KBSI
FK2-D-5 12:00-12:15	Atomic Layer Deposition of GeTe/Sb ₂ Te ₃ Superlattice for Phase Change Memory Chanyoung Yoo, Woohyun Kim, Eui-sang Park, Manick Ha, Jeong Woo Jeon, Yoon Kyeung Lee, and Cheol Seong Hwang Department of Materials Science and Engineering and Inter-University Semiconductor Research Center, Seoul National University
FK2-D-6 12:15-12:30	Tunable Diode Characteristics of Graphene via DUV Irradiations Asif Ali, Muhammad Hussain, Syed Hassan Abbas Jaffery, and Jung Jongwan Department of Nanotechnology & Advanced Materials Engineering and Graphene Research Institute, Sejong University